

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : PATENT APPLICATION

DAVID TUSCHEL ET AL. : METHOD FOR RAMAN IMAGING

OF SEMICONDUCTOR MATERIALS

Serial No. 10/610,481

Filed June 30, 2003 :

LETTER

Pittsburgh, Pennsylvania 15219 October 28, 2003

Commissioner for Patents P. O. Box 1450 Alexandria, Virginia 22313-1450

Application Processing Division Customer Correction Branch

Sir:

We are in receipt of the official filing receipt for the above-identified patent application.

In reviewing the official filing receipt we note that a Japanese application, JAPAN 2000-063085, filed March 8, 2000 is listed under Foreign Applications. Applicant did not claim priority to any foreign applications as evidenced by the enclosed copy of the Declaration of Patent Application.

It is respectfully requested that a <u>corrected</u> official filing receipt be issued and forwarded to us as soon as possible to the address listed below. If you have any questions regarding this request, please direct your call to our Legal Assistant, Angie Beyerl, at 412-562-1035.

Respectfully submitted,

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